

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Appl. No. : 10/567173 Confirmation No. 9635  
First Inventor : AMATO, Joseph M.  
Filed : February 3, 2006  
TC/A.U. : 2823  
Examiner : LEE, Hsien Ming

Docket No. : **US03 0199 US2**  
Customer No. : 65913

Title: Offset Dependent Resistor for Measuring Misalignment of  
Stitched Masks

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**RESPONSE TO REQUIREMENT FOR RESTRICTION**

Sir:

In response to the Non-Final Office Action of March 17, 2008, in which a restriction requirement has been presented, please consider the Remarks that follow beginning on page 2 of this paper.